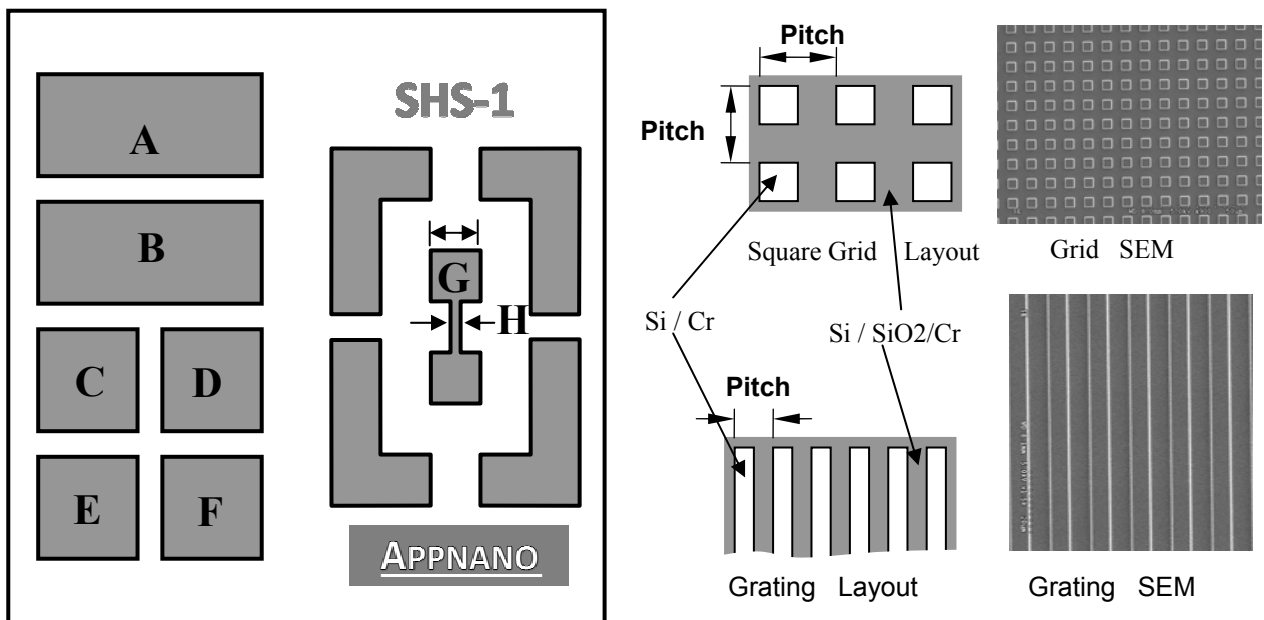


Applied NanoStructures' Step Height Standards are uniquely designed for X,Y, and Z calibration of scanning probe microscopes and profilometers. Our Step Height Standard features are defined in thermally grown silicon dioxide on silicon substrate. A layer of Cr is deposited to harden the surface. Our step height standards are available in several heights.



Feature	Description	Details
A	Square grid	3 μm pitch
B	Square grid	10 μm pitch
C	Grating	3 μm pitch
D	Grating	10 μm pitch
E	Grating	20 μm pitch
F	Grating	50 μm pitch
G	Square Pad	100 μm x 100 μm
H	Rectangular line	1000 μm x 200 nm

Ordering Information		
Part #	No of Chips	Step Height
SHS - 1	1	1 μm
SHS - 0.1	1	100 nm

NOTES :

1. The values are nominal.
2. The feature step height and pitch are not calibrated.
3. Please contact our **Distributor** in your area to **order** the products
4. For more technical information , please contact either our distributor in your area or e-mail us directly at info@appnano.com.

